

Kiyoshi YAMAGUCHI et al., S.N. 10/555,041
Page 3

Dkt. 2271/75406

Listing of Claims

The following listing of claims will replace all prior versions, and listings, of claims in the subject application:

1. (currently amended) A liquid drop discharge head, comprising:

a nozzle configured to discharge a liquid drop by using a piezoelectric element;

wherein ~~lead ingredients are not included in~~ the piezoelectric element is a stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer, and

the piezoelectric layer is formed by a piezoelectric material not including lead but having bismuth sodium titanate as main ingredients, the piezoelectric material having a sintering temperature equal to or less than 1200 °C.

Claims 2-10 (canceled).

11. (currently amended) A liquid drop discharge device, comprising:

a liquid drop discharge head configured to discharge a liquid drop;

wherein the liquid drop discharge head includes a nozzle configured to discharge the liquid drop by using a piezoelectric element, and

~~lead ingredients are not included in~~ the piezoelectric element is a stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer, and

Kiyoshi YAMAGUCHI et al., S.N. 10/555,041
Page 4

Dkt. 2271/75406

the piezoelectric layer is formed by a piezoelectric material not including lead but having bismuth sodium titanate as main ingredients, the piezoelectric material having a sintering temperature equal to or less than 1200 °C.

12. (currently amended): An image forming device configured to form an image on a recording medium by discharging a liquid drop of recording liquid, comprising:

a liquid drop discharge head configured to discharge the liquid drop;

wherein the liquid drop discharge head includes a nozzle configured to discharge the liquid drop by using a piezoelectric element, and

~~lead ingredients are not included in~~ the piezoelectric element is a stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer, and

the piezoelectric layer is formed by a piezoelectric material not including lead but having bismuth sodium titanate as main ingredients, the piezoelectric material having a sintering temperature equal to or less than 1200 °C.

13. (new) A liquid drop discharge head, comprising:

a nozzle configured to discharge a liquid drop by using a piezoelectric element;

wherein the piezoelectric element is stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer,

the piezoelectric layer is formed by a piezoelectric material not including lead but having potassium niobate as main ingredients, the piezoelectric material having a Curie temperature

Kiyoshi YAMAGUCHI et al., S.N. 10/555,041
Page 5

Dkt. 2271/75406

higher than a Curie temperature of PZT, and

an FPC for supplying a driving signal to the piezoelectric element is directly connected to an end surface electrode of the stacked layer type piezoelectric element by solder.